

This listing of claims will replace all prior versions, and listings of claims in the application:

Listing of Claims:

- 5 **Claim 1 (currently amended):** A cleaning system, comprising:
 a combination of a substrate and a frame layer arranged on the substrate to form a chamber together with the substrate;
 a sealed up body formed with a cleaning room;
 a rotating device located within the cleaning room of the sealed up body,
10 wherein the combination of the substrate and the frame layer is fixed on the rotating device; and
 a cleaning device, which is disposed in the cleaning room of the sealed up body, for cleaning the chamber of the substrate by a cleaner ejected directly from the cleaning device into the chamber in a direction opposite to a direction of a
15 centrifugal force of the combination of the substrate and the frame layer, wherein the rotating device is configured to fix the combination of the substrate and the frame layer with the chamber facing the cleaning device, and an interface between the substrate (64) and the frame layer (66) is substantially perpendicular to an interface between the rotating device (52) and the combination of the substrate (64)
20 and the frame layer (66).
- Claim 2 (previously presented): The cleaning system according to claim 1, wherein the sealed up body includes a lower element, a periphery wall connected to the lower element, and an upper cover connected to the periphery wall.
- Claim 3 (previously presented): The cleaning system according to claim 2,
25 wherein the rotating device is located on the lower element of the sealed up body.
- Claim 4 (previously presented): The cleaning system according to claim 2, wherein the cleaning device is mounted on the periphery wall of the sealed up body.
- Claim 5 (previously presented): The cleaning system according to claim 2,
30 wherein the cleaner of the cleaning device is nitrogen or carbon dioxide.